



# plasma process group

## 6 cm RF Ion Beam Source



### Features

- **RF Discharge (no filament)**
- **Variety of Process Gases**
- **Shaped Molybdenum Grids**
- **Easy Maintenance**
- **Small Size Fits in Tight Spaces**

### Applications

- **Sputter Deposition**
- **Etching**
- **Ion Beam-Assisted Deposition**
- **Materials Research**

### Description

Plasma Process Group now offers a 6 cm RF ion beam source for research and manufacturing environments, ideal for assist or etch applications. Using RF discharge (no filaments) minimizes maintenance requirements and allows for a wider range of process gases including many reactive species.

New technology developed by Plasma Process Group has dramatically extended the operating life of RF sources in conductive deposition and etching, making RF a good choice for all types of processes.

Shaped Molybdenum grids with a 25cm focal point are standard for the 6 cm ion beam source allowing for convergent or divergent beams. RF ion beam sources are typically flange-mounted, but custom mounting is available.

We understand that every ion beam installation is unique and we're ready to discuss the requirements of your specific application.

*Whether you're in research or production, Plasma Process Group is committed to providing the best support possible. Help is just a phone call away (or email if you prefer). Our people have many years of experience with ion beam sources, systems, and applications, and we're happy to share that with you. Give us a call.*

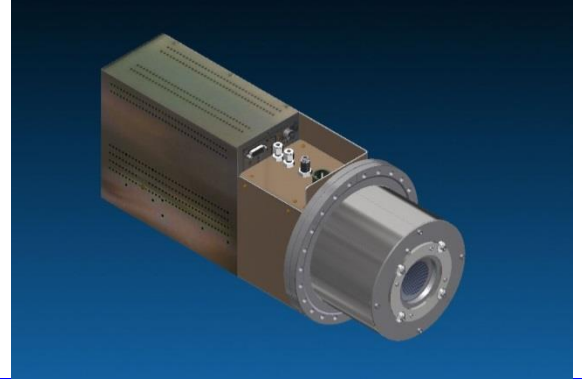
## Specifications

## 6 cm Source

Internal Mount

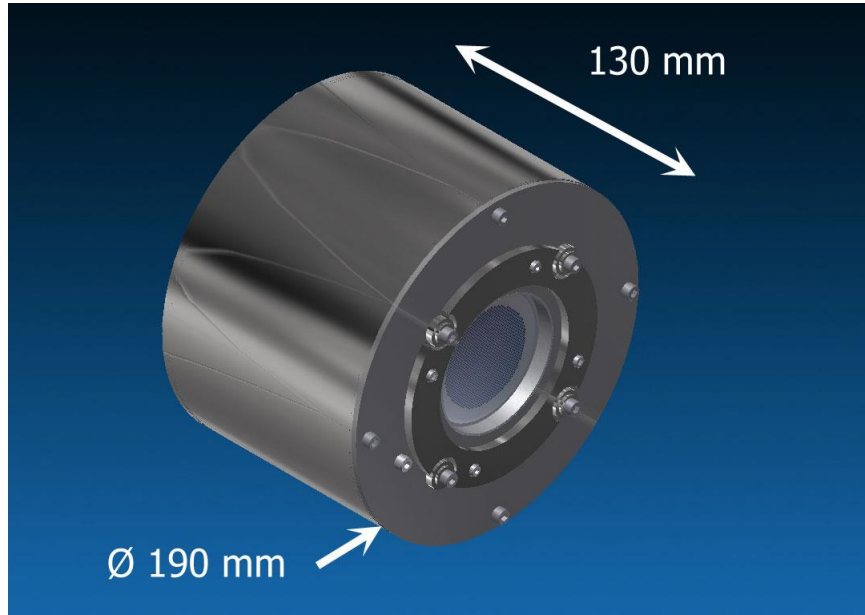


Flange Mount (10" CF)



Ion source	6 cm RF
Model number	06RF16
Beam size at grids	6 cm
Beam current	25 – 200 mA
Beam energy	50 – 1500 eV
Grid material	Molybdenum, 25cm Focal Point
Beam neutralization	RF Neutralizer (sold separately)
Cooling	Water cooled antenna only
Power supply	I-BEAM™ 703
Weight	3.6 Kg (8 lbs)

Dimensions



**Ordering Information:** The 6 cm Ion beam source is available with options such as flange or internal mounting kits to facilitate installation. Please contact us to configure your ion source.

**Suggested Accessories:**

IBEAM 703

I-BEAM™ 703 RFS/RFN Power Supply with built-in 500W RF generator

504424B

RF Neutralizer

504552A / 504553A

ATN-10 Matching Network for source / PT-II Auto Controller for Matching Network



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